

ABSTRACT

WAREHOUSE SELECTION METHOD AND APPARATUS, COMPUTER DEVICE, AND STORAGE MEDIUM

Embodiments of the present disclosure belong to the field of wafer management. Disclosed are a warehouse selection method and apparatus, a computer device, and a storage medium. In the embodiments of the present disclosure, the method includes: acquiring a warehouse list, where the warehouse list stores a stocker identification and corresponding historical work parameter information of each of a plurality of stockers; determining, according to the properties and the storage capacity, whether there is at least one idle stocker, among the plurality of stockers in the warehouse list, that is available for storing the wafers to be transported; acquiring, upon determining that there is no idle stocker in the target warehouse, at least one temporary stocker in a temporary warehouse adjacent to the target warehouse, and modifying temporary status information of each of the at least one temporary stocker; and acquiring, based on the target wafer storage request, historical work parameter information and a corresponding stocker identification of each of the at least one temporary stocker.

FIG. 1